

Supplementary Information

A Micro-Fabricated Force Sensor Using an All Thin Film Piezoelectric Active Sensor. *Sensors* 2014, 14, 22199-22207

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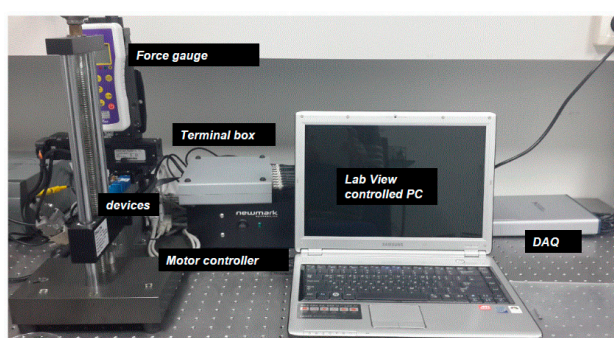
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Figure S1. Experimental set-up for micro-fabricated piezoelectric force sensor.



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